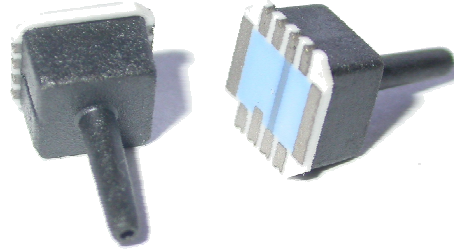


HYBRID SERIES PRESSURE SENSORS

The hybrid series MEMS made piezoresistive pressure sensors provides a convenient way to use Surface mount technology with a flexible way of air connection. Due to the production process these sensors are ideal for high volume applications and automated assy. Two kind of air connections are available, a cap with hole and a cap using 1/8" tube connection.

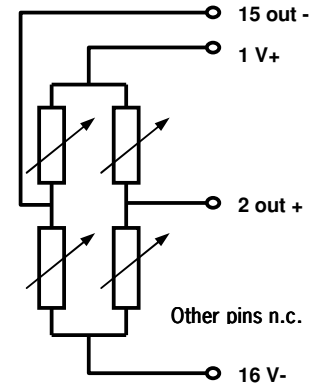
Available in: absolute version and gauge version; Pressure range 15, 30, 100 and 150 Psi.



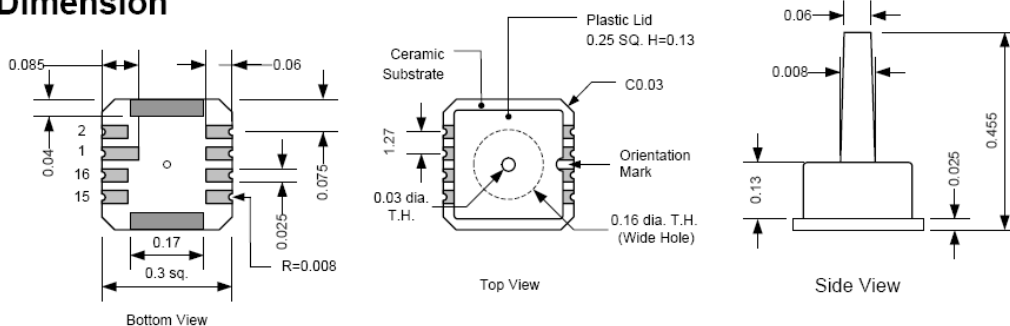
Electrical Characteristics

Performance Characteristic at Vcc =5V excitation @ 25 °C.

Parameter	Min	Typ	Max	Units.
Supply Voltage	2.7	5	10	V
Pressure range (fs)		15		psi
Offset	-50	0	50	mV
Span Output	105	145	175	mV
Bridge Impedance	2.7	3.3	4.0	KΩ
TC Span (0-50 °C)	-16	-22	-28	%FS/100°C
TC Offset (0-50 °C)		±7		%FS/100°C
Response time		1		ms
Pressure overload			3X	psi
Operating temperature	-40		85	°C
Storage temperature	-40		125	°C



Dimension



Note: All sizes in Inches
 Max soldering 260 °C / 7 seconds

